Dr. Edin Sarajlic

*SmartTip B.V.*

*e.sarajlic@smarttip.nl*

**Biography**

Edin Sarajlic received in 2001 the M.Sc. (Cum Laude) in mechanical engineering from The University of Twente, The Netherlands. In 2005 he completed the Ph.D. course in Transducers Science and Technology Group (TST) at MESA+ Research Institute. From 2005 till 2008 he was a Postdoctoral Researcher in the MEMS Lab of Prof. Hiroyuki Fujita at Institute of Industrial Science, The University of Tokyo, Japan. In 2008 he joined SmartTip B.V. a company specialized in the design, production and packaging of dedicated special purpose scanning microscopy probes. His research interest focuses on the development of micromechanical systems and micromachining methods for their fabrication.

**Abstract - Wafer-scale fabrication of advanced scanning microscopy probes by corner lithography**

Corner lithography is a wafer-scale processing method based on standard micromachining techniques and conventional optical photolithography. This relatively simple manufacturing method allows fabrication of 3-dimensional nanometer-sized structures in a wide range of materials. The use of corner lithography for fabrication of the FluidFM microfluidic probes will be discussed. An overview of different applications of the FluidFM probes such as nanopatterning, single-cell analysis and 3D metal printing will be given.